

[86.03/66.25] Dispositivos Semiconductores

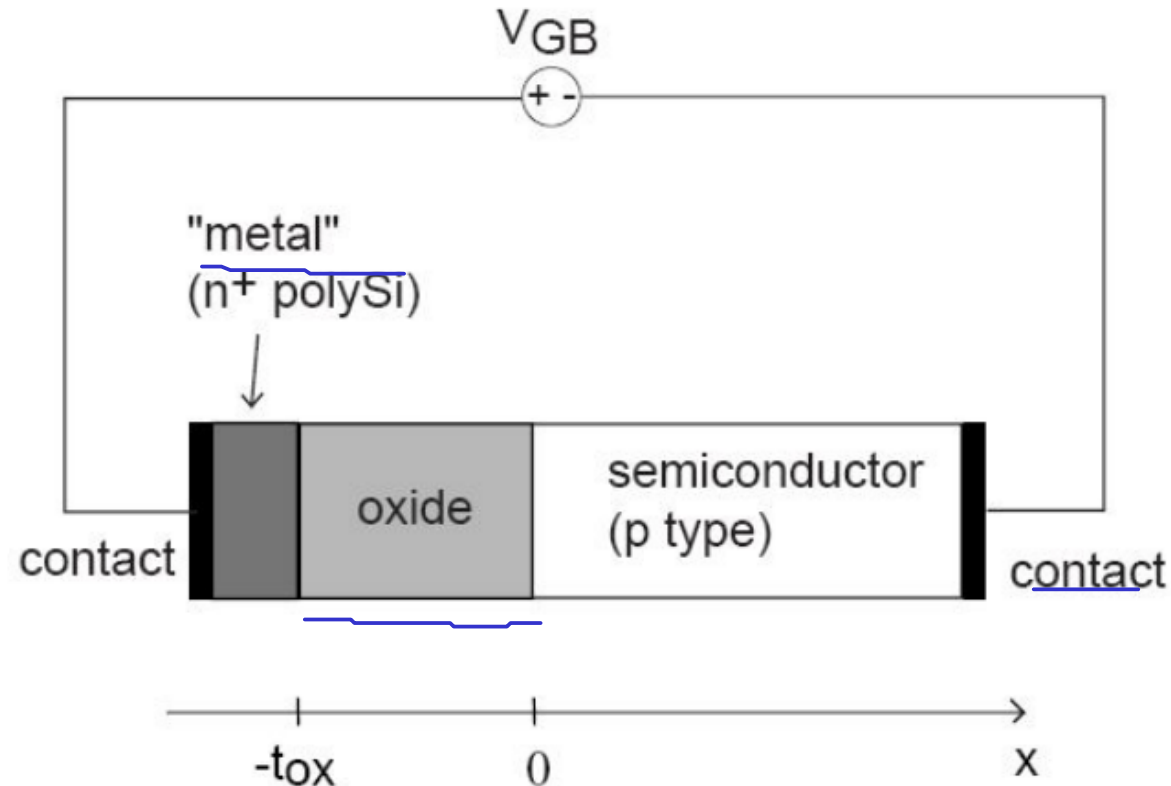
1er Cuatrimestre de 2020

Juntura MOS

Se tiene una juntura MOS construida con poly N+ y substrato P de la cual se conocen los siguientes datos:

- $t_{ox} = 150 \text{ \AA}$
- $N_A = 3 \cdot 10^{15} \text{ cm}^{-3}$
- $V_{FB} = \underline{-0.876 \text{ V}}$
- $V_T = 0.884 \text{ V}$

Hallar ϕ_B , C'_{OX} , x_d , Q'_{SCR} , ΔV_{BULK} y ΔV_{OX} cuando $V_{GB} = 0.2 \text{ V}$.



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$$C'_{OX} = \frac{\epsilon_{SiO_2}}{t_{ox}}$$

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- $\epsilon_0 = 88.5 \frac{fF}{cm}$
- $t_{ox} = 150 \text{ \AA}$
- $n_i = 10^{10} \text{ cm}^{-3}$
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- $v_{th} = 25.9 \text{ mV}$

Dos de los valores pedidos no dependen de la tensión...

$$C'_{OX} = \frac{\epsilon_{SiO_2}}{t_{ox}} = \frac{3.9 \epsilon_0}{150 \text{ \AA}} = 23 \frac{nF}{cm^2}$$

$$1 \text{ \AA} = 10^{-10} \text{ m}$$

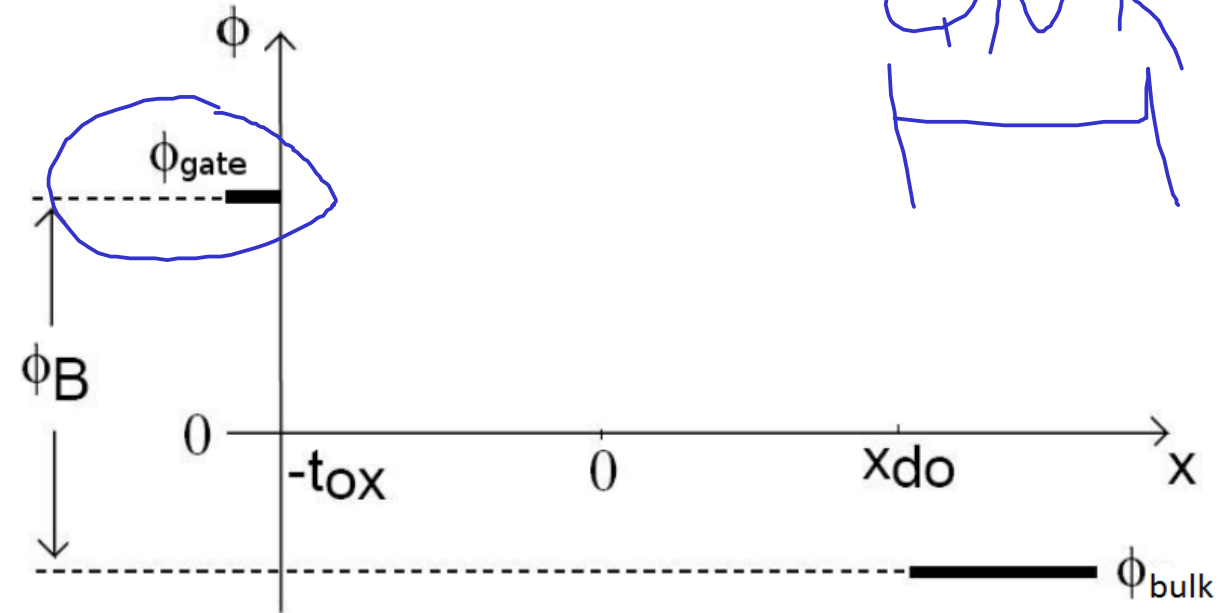
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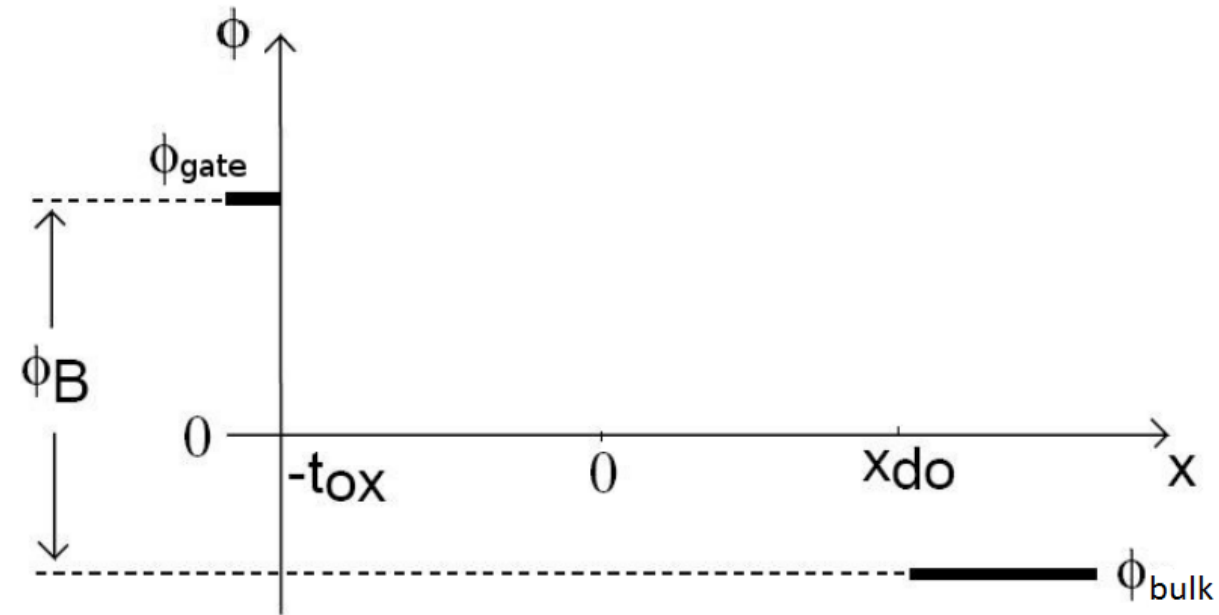
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Gate : PolySi N^+ → $\phi_{gate} = 550 mV$

Bulk : Tipo P → $\phi_{bulk} = -v_{th} \ln\left(\frac{N_A}{n_i}\right) = -326 mV$



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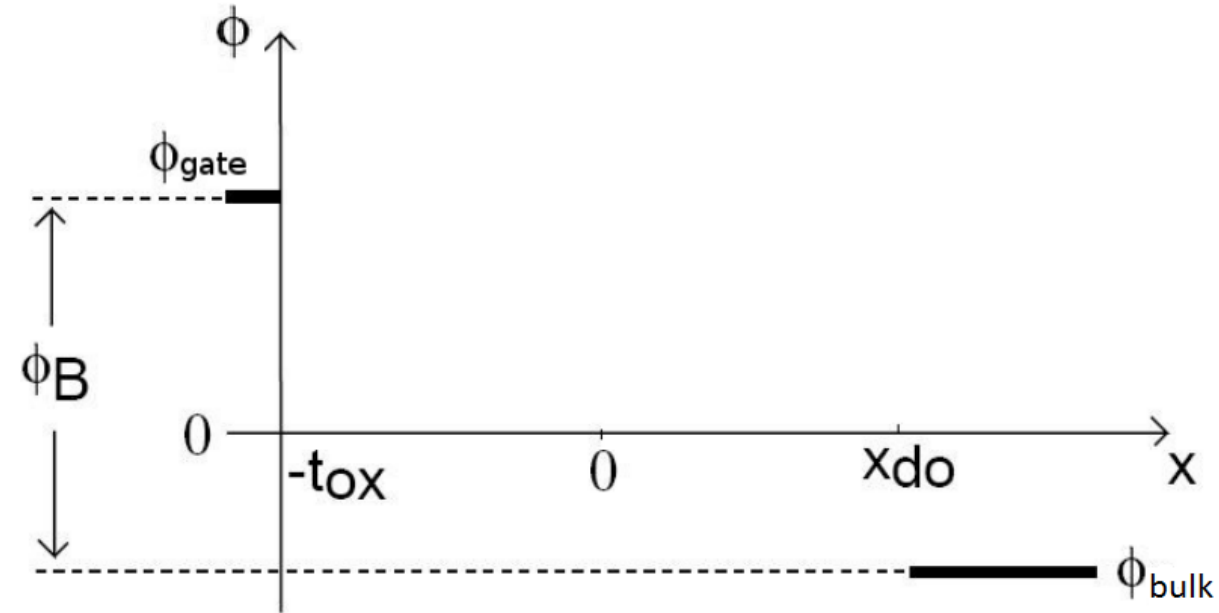
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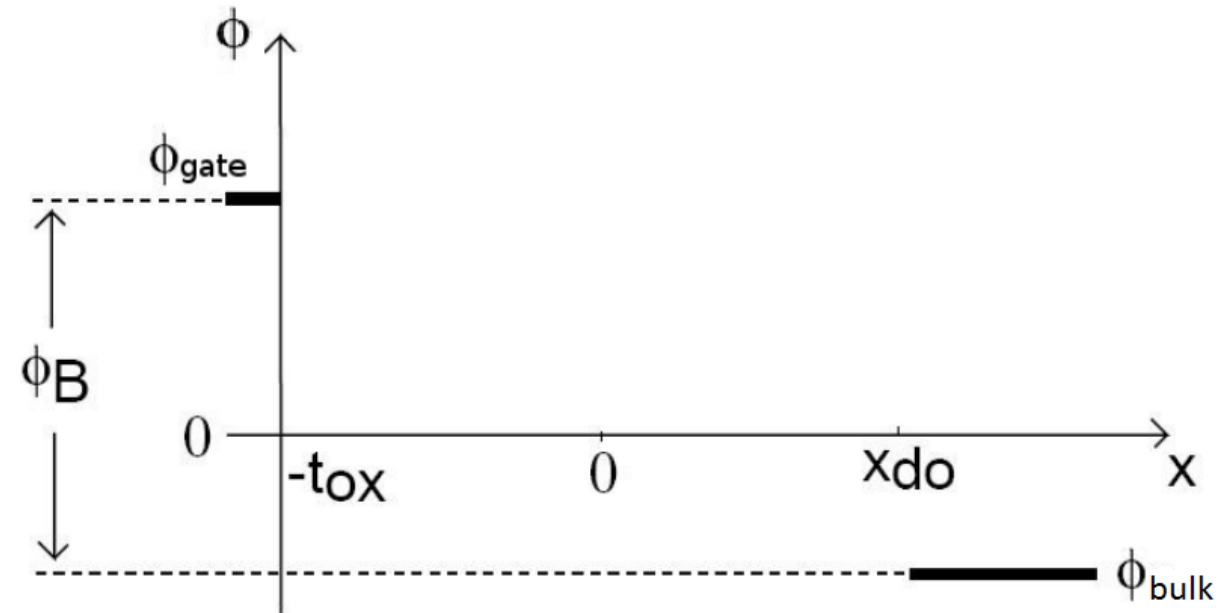
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$$(V_{FB} = -876 mV = -\phi_B)$$

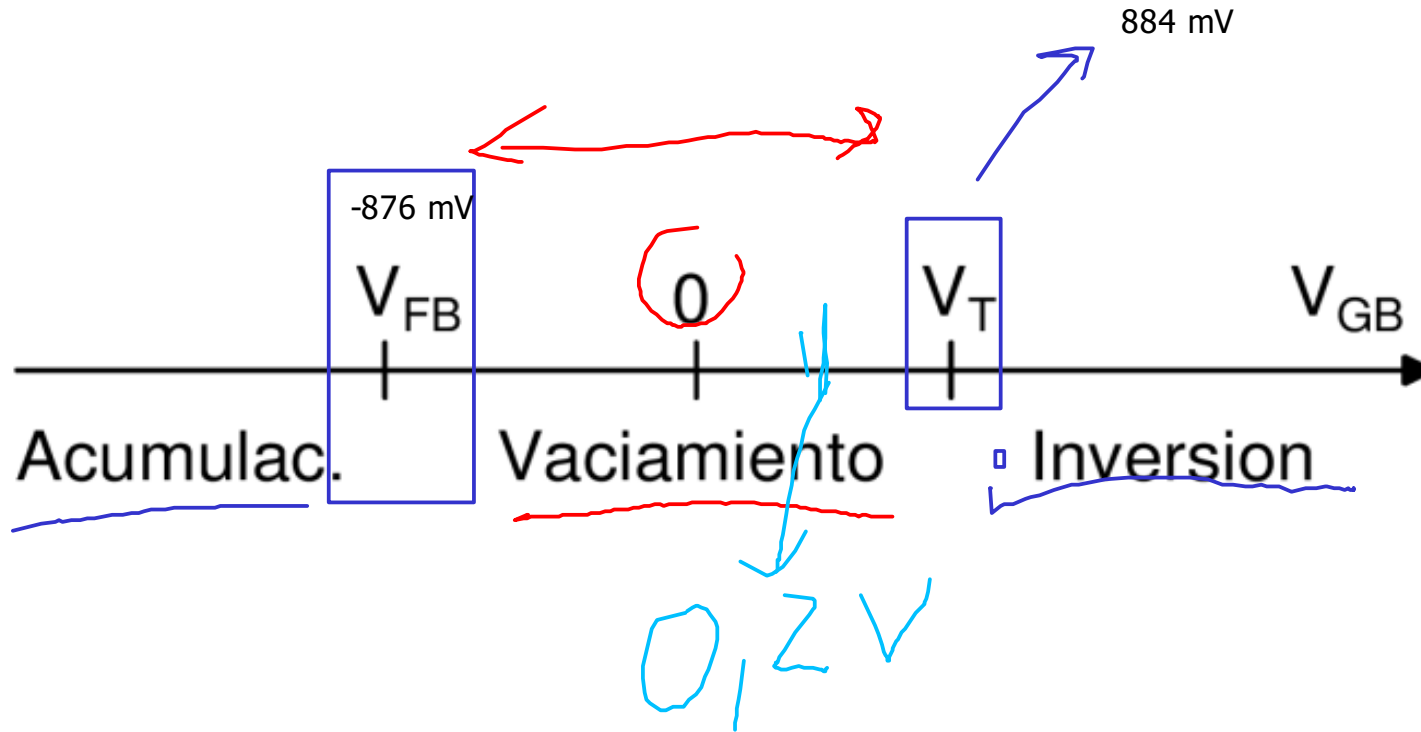


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¿En que régimen estamos?

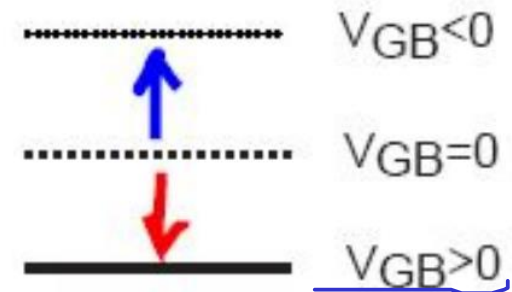
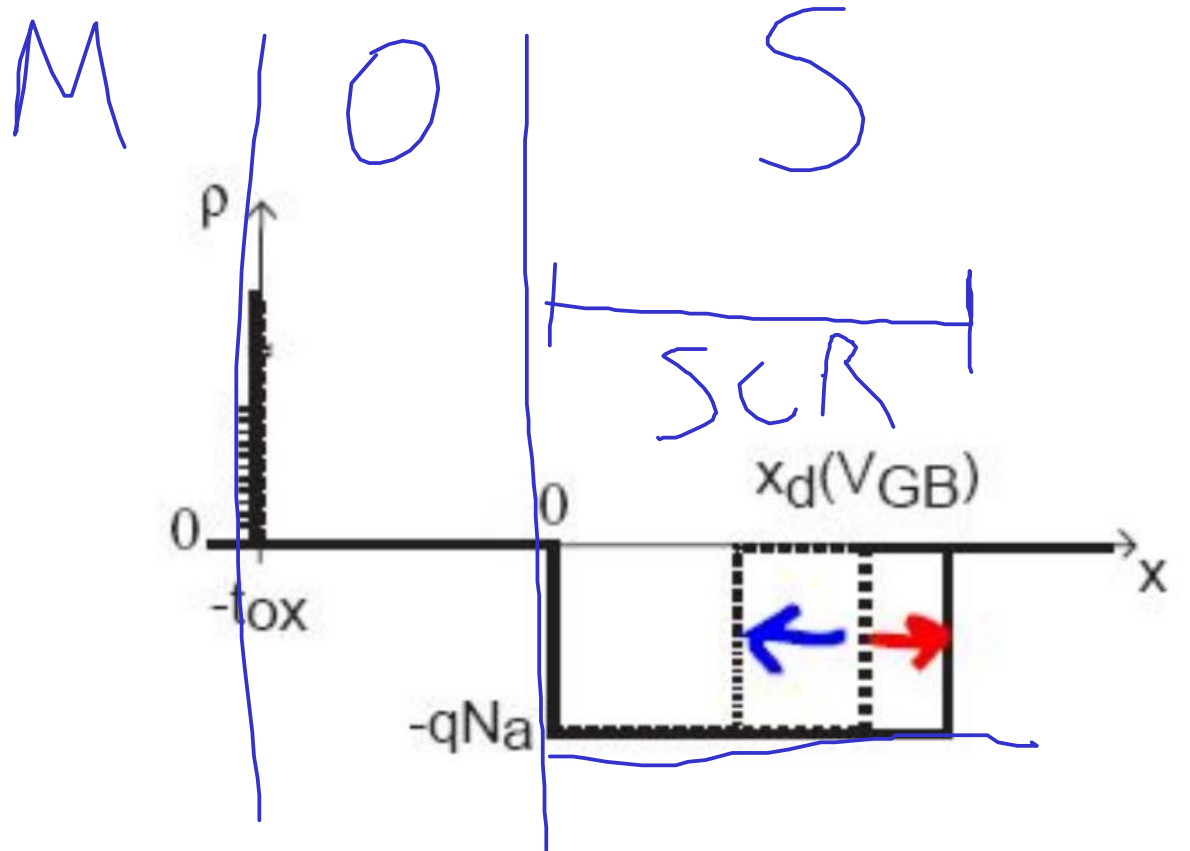
$$V_{GB} = 0,2V$$



Como estamos en vaciamiento...

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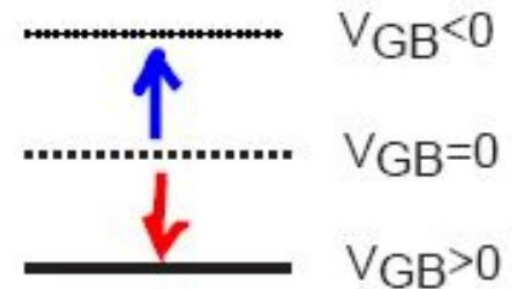
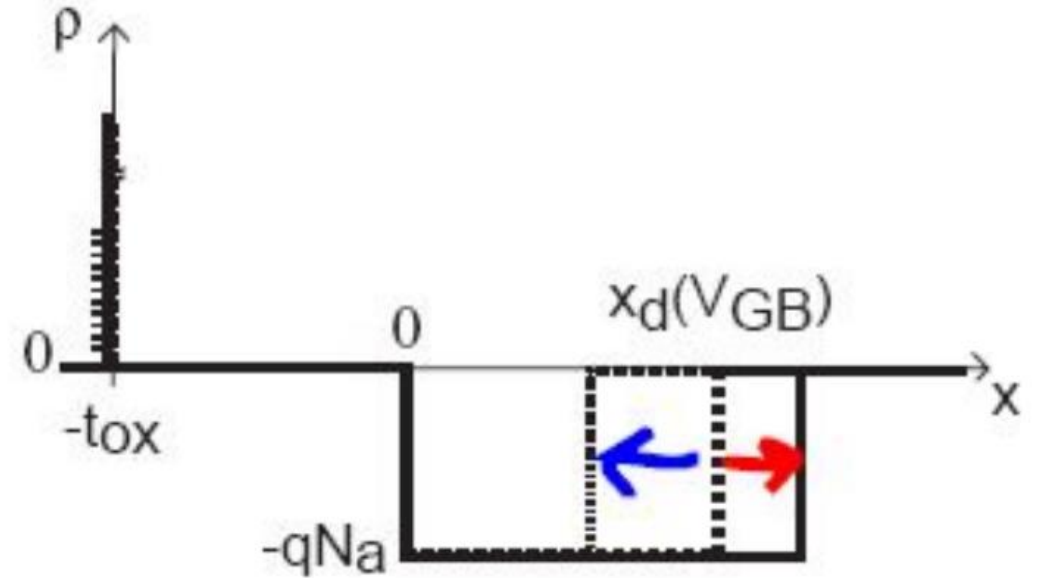
$$x_d = \frac{\epsilon_{si}}{C'_{OX}} \left[\sqrt{1 + \frac{4(\phi_B + V_{GB})}{\gamma^2}} - 1 \right]$$



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$$\gamma = \frac{1}{C'_{OX}} \sqrt{2 \epsilon_{si} q N_A} \rightarrow \boxed{\gamma} = \sqrt{V}$$



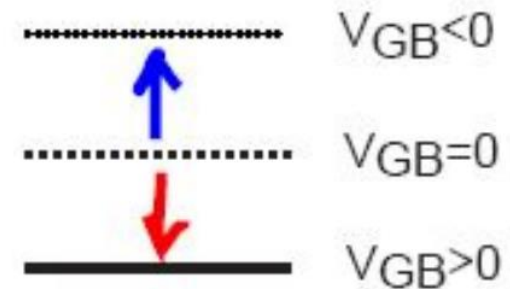
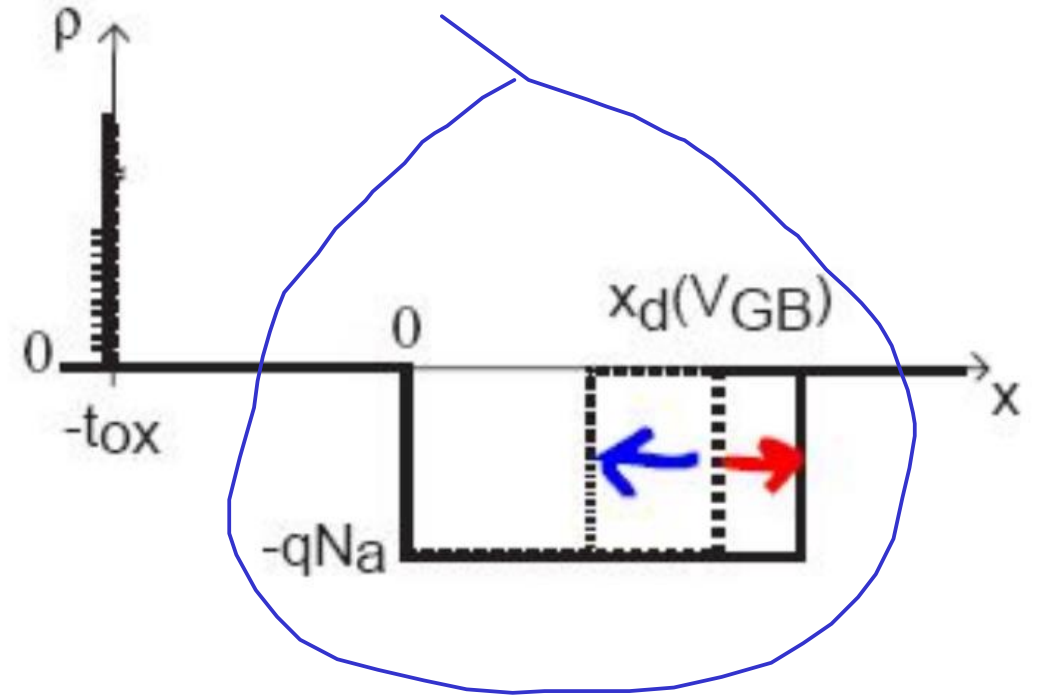
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$$\gamma = 1.37 \text{ V}^{1/2}$$

$$x_d = 366 \text{ nm}$$



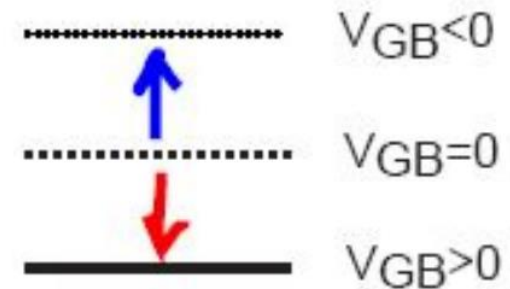
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$$Q'_{SCR}(V_{GB}) = -q N_A x_d(V_{GB})$$

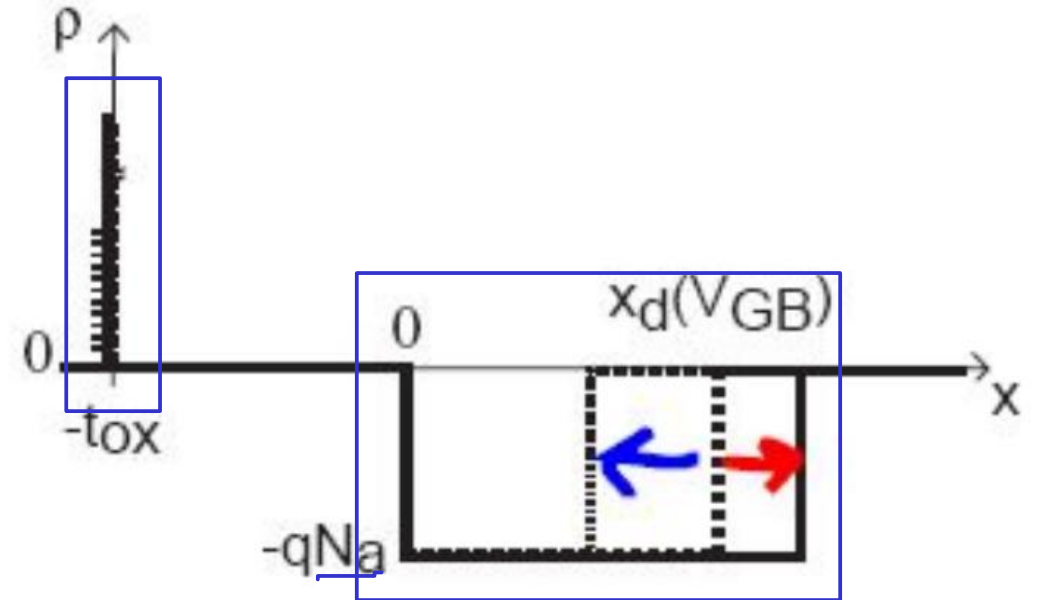


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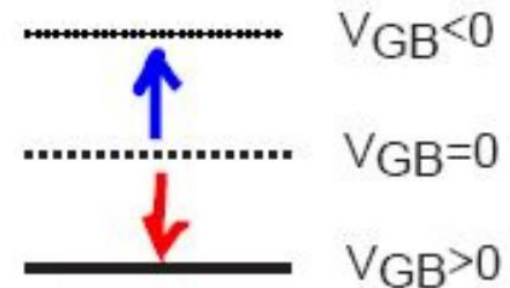
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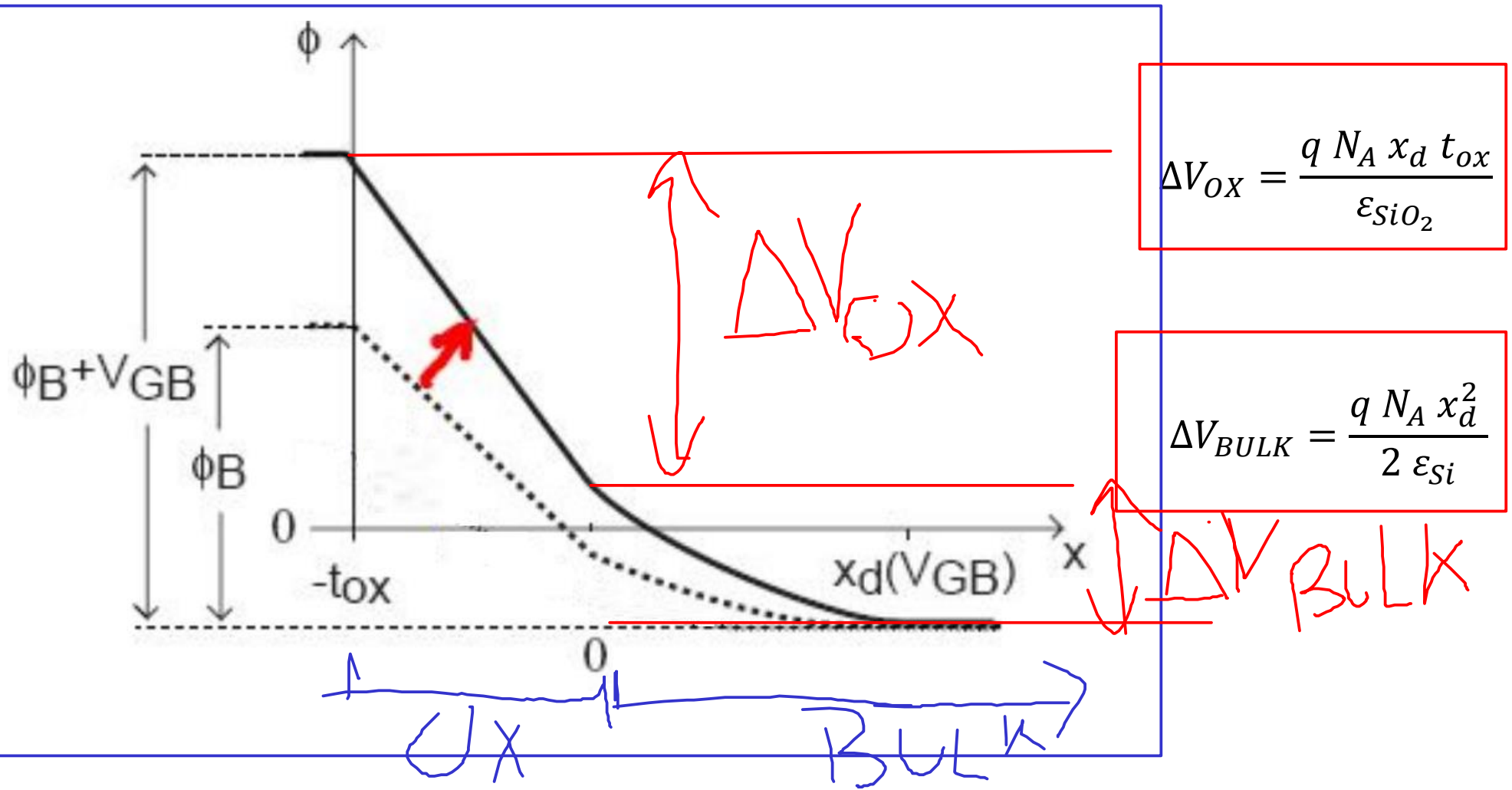
$$Q'_{SCR} = -1.76 \frac{C}{cm^2}$$

$$(|Q'_{M-Ox}| = |Q'_{SCR}|)$$

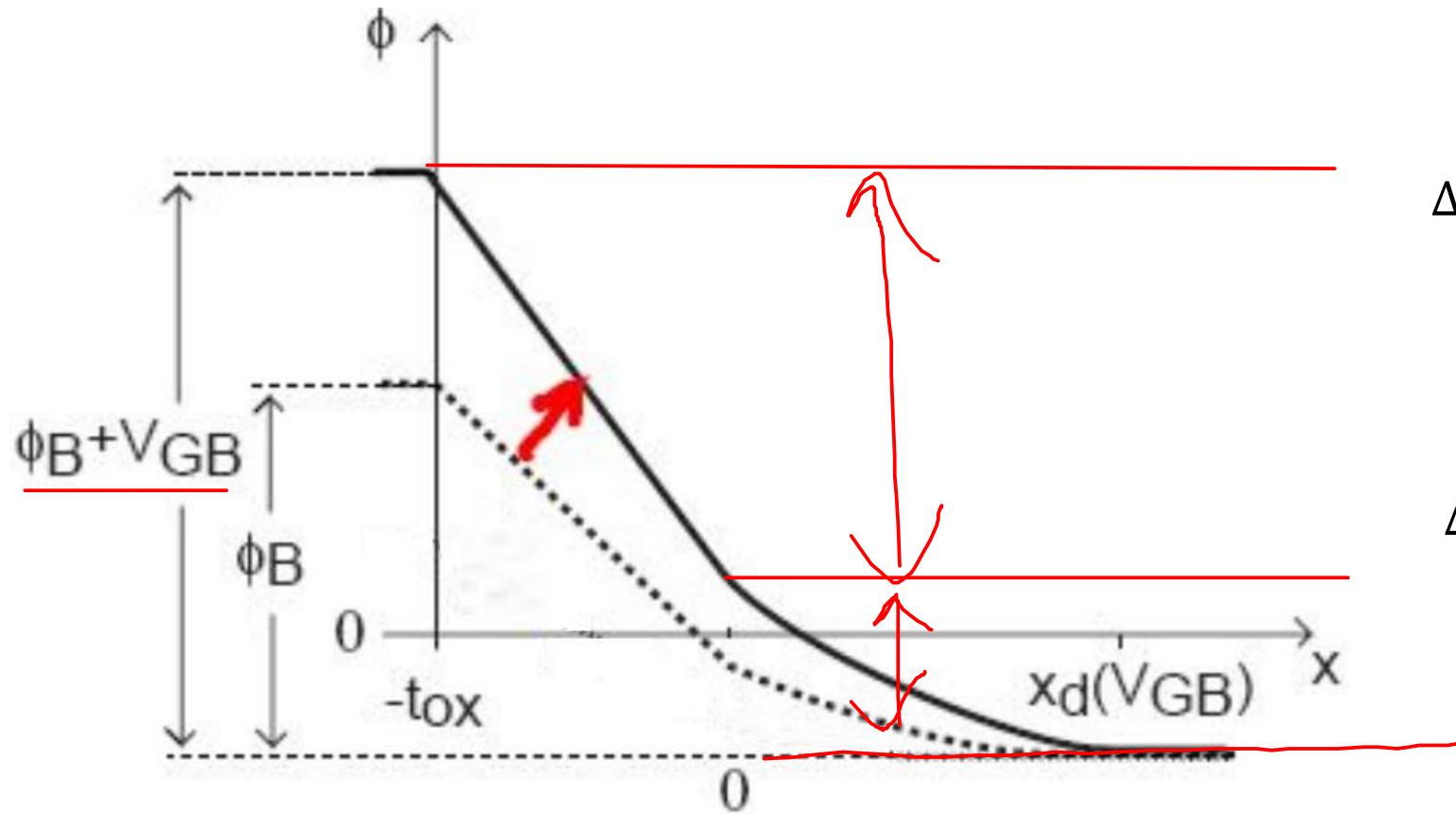


Los potenciales cuando aplicamos tensión a la junta...

Los potenciales cuando aplicamos tensión a la juntura...



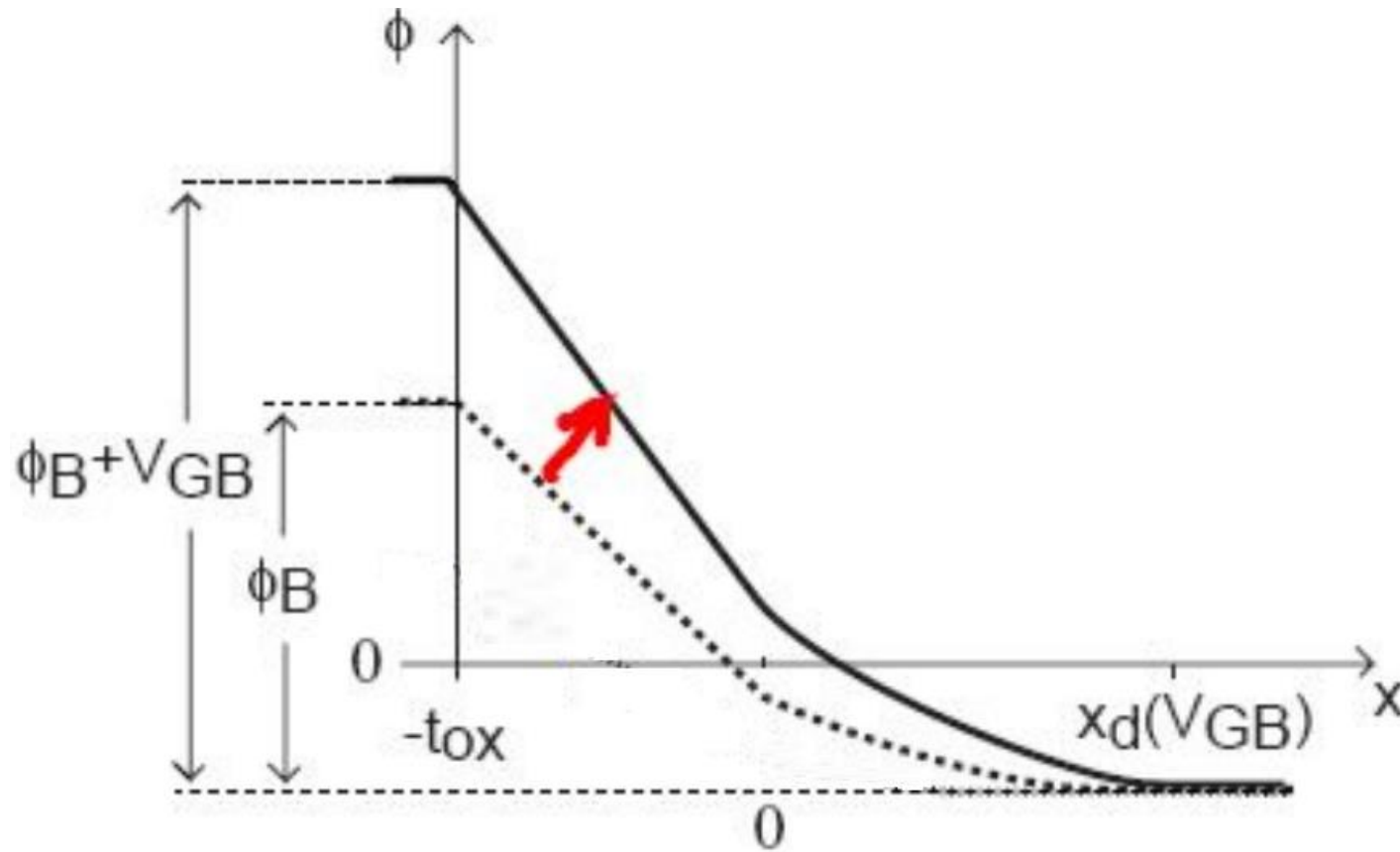
Los potenciales cuando aplicamos tensión a la juntura...



$$\Delta V_{OX} = \frac{q N_A x_d t_{ox}}{\epsilon_{SiO_2}} = \underline{765 \text{ mV}}$$

$$\Delta V_{BULK} = \frac{q N_A x_d^2}{2 \epsilon_{Si}} = \underline{311 \text{ mV}}$$

Los potenciales cuando aplicamos tensión a la juntura...



$$\Delta V_{OX} = \frac{q N_A x_d t_{ox}}{\epsilon_{SiO_2}} = 765 \text{ mV}$$

$$\Delta V_{BULK} = \frac{q N_A x_d^2}{2 \epsilon_{Si}} = 311 \text{ mV}$$

Notemos que: $V_{GB} + \phi_B = \Delta V_{OX} + \Delta V_{BULK} = \underline{1076 \text{ mV}}$